



Application No.: 10/060,826  
Docket No.: IB-1581/LBNL 207/10413310

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Daniel S. Pickard et al.

Application No.: 10/060,826

Confirmation No.: 9952

Filed: February 1, 2002

Art Unit: 2821

For: MATCHING NETWORK FOR RF PLASMA  
SOURCE

Examiner: W. Lee

**AMENDMENT IN RESPONSE TO NON-FINAL OFFICE ACTION**

MS Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office action dated August 24, 2004 please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** and new claims begin on page 2 of this paper.

**Remarks** begin on page 6 of this paper.

01/27/2005 AWONDAF1 00000100 10060826

01 FC:2201 100.00 DP  
02 FC:2202 100.00 DP